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Atomically thin films of MoS<sub>2</sub> have emerged as promising building blocks for flexible electronics. Recently, we reported high-performance CVD-grown MoS<sub>2</sub> field effect transistors (FETs) on paper with inkiet-printed Ag contacts and h-BN dielectric [1]. Here, for the first time, we study the low-frequency noise (LFN, or 1/f noise) behaviour on the same devices, which can provide useful insights on the physical mechanisms at play in the fabricated FETs. Fig. 1 (a) shows a photograph and an optical micrograph of a fabricated FET. A typical FET transfer characteristic is shown in Fig. 1 (b). LFN is expressed using Hooge's law:  $S_{I_{DS}} = A I_{DS}^2 / f^{\gamma}$ , where  $S_{I_{DS}}$  is the power spectral density (PSD) of the channel current ( $I_{DS}$ ), A the noise amplitude, and f the frequency. The PSD and the normalized PSD of  $I_{DS}$  for different drain voltages ( $V_{DS}$ ) are shown in Fig. 1(c), and its inset, respectively. In the latter, the spectra nearly overlap, indicating a good normalization. Fig. 2 (a) shows the PSD of  $I_{DS}$  for different gate voltages  $(V_{GS})$ . The dependence of 1/A and  $\gamma$  (the exponent of f) on  $V_{GS}$  is reported in Fig. 2 (b). The linear fit of 1/A suggests that mobility fluctuations are at the origin of the observed noise, in agreement with the Hooge model, and  $\gamma$ ~1. Finally, Fig. 2 (c) shows the Hooge parameter  $\alpha_H = A \cdot N$ , where N is the total number of carriers in the channel. This parameter is comparable with those of mechanically exfoliated monolayer MoS<sub>2</sub> FETs [2].

## References

[1] S.Conti et al., arXiv:1911.06233v1

[2] V. K. Sangwan et al., Nano Letters (2013)

Figures



**Figure 1:** (a) Optical image of the paper substrate and of a FET (scale bar: 200  $\mu$ m). (b) Transfer characteristic of a studied FET. Inset: Schematic image of the device. (c) PSD of the channel current for V<sub>DS</sub> from 20 mV to 1 V, with V<sub>GS</sub> = 6 V. Inset: normalized PSD with respect to the current.



**Figure 2:** (a) PSD of the channel current for V<sub>GS</sub> ranging from 2 V to 8 V, with V<sub>DS</sub> = 1 V. (b) Noise amplitude (left axis) and exponent of the frequency (right axis) as a function of gate voltage. (c) Hooge parameter as a function of V<sub>GS</sub>.